THE HONG KONG POLYTECHNIC UNIVERSITY
香港理工大學

University Research Facility in Materials Characterization and Device Fabrication
材料與器件中心實驗室

UMF Equipment – Fischione 1040 Nanomill

Fischione's Model 1040 NanoMill® TEM specimen preparation system is an excellent tool for creating the high-quality thin specimens needed for advanced transmission electron microscopy imaging and analysis. It is ideal for both post-FIB (focused ion beam) processing and the enhancement of conventionally prepared specimens.

Specifications:

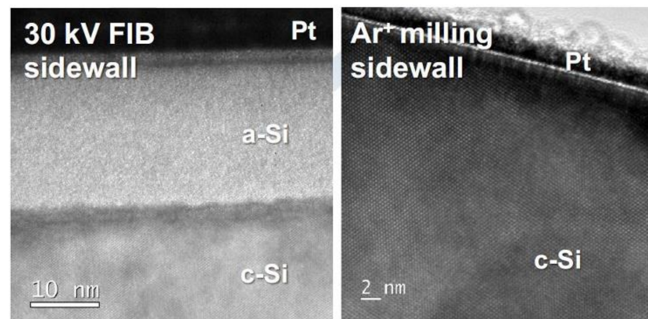
- Ultra-low-energy, inert-gas ion source.
- Concentrated ion beam with scanning capabilities.
- Removes damaged layers without re-deposition.
- Ideal for post-focused ion beam processing.
- Enhances the results from conventionally prepared specimens.
- Room temperature to cryogenically cooled NanoMilling SM process.
- Rapid specimen exchange for high-throughput applications.
- Computer-controlled, fully programmable, and easy to use.
- Contamination-free, dry vacuum system.

Please refer to https://www.fischione.com/products/ion-beam-preparation/model-1040-nanomill®-tem-specimen-preparation-system for further details of the system.

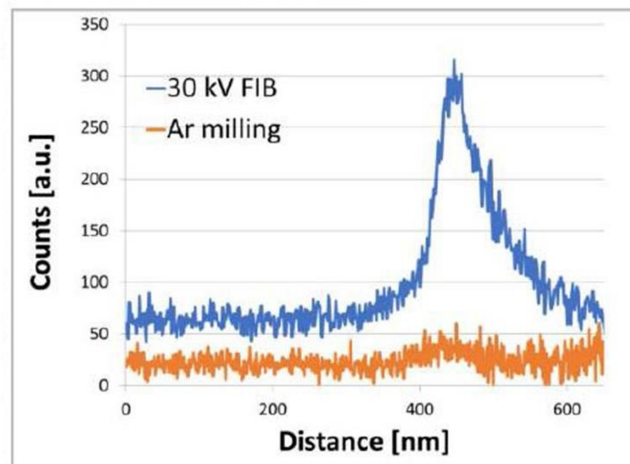
For training arrangement, please log on URFMS website for further details of upcoming training session.

For any enquiry, please contact Dr. Wei Lu (Tel: 34002077; Email: wei.lu@polyu.edu.hk).

Applications:



EDS line scan



Removal of amorphous damage layer in Si